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AF

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Takahiro HAYASHI et al.

Group Art Unit: 1744

Application No.: 10/082,250

Examiner: V. PATEL

Filed: February 26, 2002

Docket No.: 112052

For: APPARATUS FOR GENERATING HYDROGEN GAS

REQUEST FOR RECONSIDERATION AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the September 9, 2005 Office Action, reconsideration of the rejection and objections is respectfully requested in light of the following remarks.

Claims 1-28 are pending.

Applicants appreciate the courtesies shown to Applicants' representative by Examiner Patel in the December 6, 2005 personal interview. Applicants' separate record of the substance of the interview is incorporated into the following remarks.

I. Rejection Under 35 U.S.C. §102(e)

Claims 1-28 were rejected under 35 U.S.C. §102(e) as allegedly being anticipated by U.S. Patent No. 6,802,875 ("Kimbara"). This rejection is respectfully traversed.

The Patent Office alleges that Kimbara teaches a reactor 26 with a catalyst that is heated to produce a hydrogen gas. The Patent Office further alleges that it is clear that a liquid-film is formed by the liquid flowing over the catalyst and reactor 26, and thus Kimbara is allegedly capable of forming a liquid-film on the catalyst. The Patent Office also alleges